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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Seamus Paul Whiston et al

Serial No: Confirmation No.: 09/480,223 4079

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For:

January 10, 2000 METHOD FOR FORMING A DMOS DEVICE AND A DMOS

DEVICE

Examiner:

Huynh, Yennhu B.

Art Unit:

## CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

The undersigned hereby certifies that this document is being placed in the United States mail with first-class postage attached, addressed to Commissioner for Patents, Washington, D.C. 20231, on the 21st day of April, 2003.

Steven J. Henry, Reg. No. 27,900

**COMMISSIONER FOR PATENTS** WASHINGTON, D.C. 20231

## REQUEST FOR RECONSIDERATION

In response to the Final Action mailed October, 2002, Applicant requests reconsideration of the obviousness rejections under §103, for the reasons detailed below.

## **REMARKS**

Briefly, none of the prior art references discloses the formation of a body region in a DMOS device -- or, indeed, in any other device in which the body region is formed by steps (a) and (b) of claim 1.

The principal reference is Hshieh '408. Hshieh discloses a method performing a body region 64 in a DMOS device. In general, it is directed toward a vertical DMOS (the DMOS device), but Hshieh does suggest that his methods also be used in the fabrication of a lateral DMOS (LDMOS) device. In a vertical DMOS, the current flows vertically from the top to the bottom, while in a lateral DMOS the current flows laterally. The DMOS described in the specification of the present application is a lateral DMOS. However, Applicant does not wish to limit claim 1 to an LDMOS. In the specification at page 13, lines 13-20, we have described other DMOS devices which could be fabricated using the disclosed method, one of which is a vertical DMOS.

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Sir: